



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application of: Nakayama et al.

Application No. 10/003,042

Filed: November 13, 2001

Confirmation No. 1236

For: METHODS AND DEVICES FOR
MEASURING A SURFACE PROFILE OF
AN OPTICAL ELEMENT

Examiner: Samuel A. Turner

Art Unit: 2877

Attorney Reference No. 4641-61595-01

CERTIFICATE OF MAILING

I hereby certify that this paper and the documents referred to as being attached or enclosed herewith are being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: COMMISSIONER FOR PATENTS, P.O. BOX 1450, ALEXANDRIA, VA 22313-1450 on the date shown below.

Attorney
for Applicant(s)

Date Mailed August 5, 2004

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AMENDMENT AND REPLY TO OFFICE ACTION

This paper is submitted in reply to the Office action, dated March 12, 2004. Please amend the subject application as follows:

Amendments to the Title begin on page 2.

Remarks begin on page 3.

Amendments to the Title

Please replace the title of this application, as filed, with the following:

**Methods for Measuring a Surface Profile of an Optical Element By
Determining Profile Differences From Interference Phase Distributions**